

# Electron Microscopy II

- Transmission Electron Microscopy (TEM)
- Scanning Transmission Electron Microscopy (STEM)
- Scanning Electron Microscopy (SEM)

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200 nm

## Electron Microscopy Methods

Transmission Electron Microscopy (TEM)

- Bright / Dark Field (BF/DF)
- High-Resolution Transition Electron Microscopy (HRTEM)
- Energy-Filtered (EFTEM)
- Electron Diffraction (ED)

Scanning Transmission Electron Microscopy (STEM)

- Bright / Dark Field (BF/DF-STEM)
- High-Angle Annular Dark Field (HAADF-STEM)

Analytical Electron Microscopy (AEM)

- X-ray Spectroscopy
- Electron Energy-Loss Spectroscopy (EELS)
- Electron Spectroscopic Imaging (ESI)

Scanning Electron Microscopy (SEM)

- Secondary Electrons (SE)
- Back-Scattered Electrons (BSE)

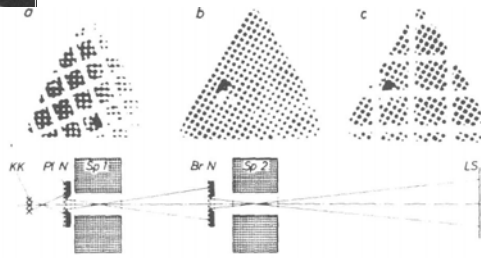
## Development of the First Transmission Electron Microscope



**1927 Hans Busch:** Electron beams can be focused in an inhomogeneous magnetic field.

**1931 Max Knoll and Ernst Ruska** built the first TEM.

**1986 Nobel prize for Ruska**

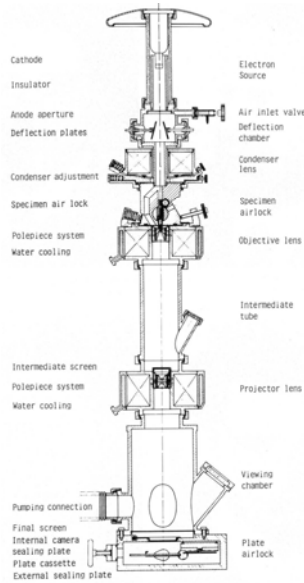


a) Einstufiges Bild eines Platin-Netzes vor Spule 1 durch Spule 1;  $M$  130 : 1  
 b) Einstufiges Bild eines Bronze-Netzes vor Spule 2 durch Spule 2;  $M$  48 : 1  
 c) Zweistufiges Bild des Platin-Netzes vor Spule 1 durch Spule 1 und Spule 2;  $M$  174 : 1  
 zusammen mit dem einstufigen Bild des Bronze-Netzes vor Spule 2;  $M$  48 : 1

Knoll, Ruska, Z. Phys. **78** (1932) 318

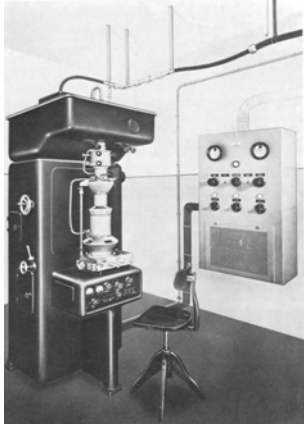
History of Electron Microscopy

## 1938 First Siemens Electron Microscope (Resolution ca. 13 nm)

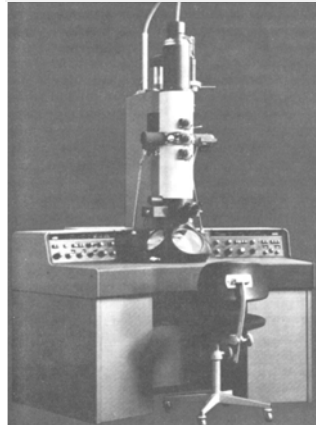


History of Electron Microscopy

## Transmission Electron Microscopes



1939: first TEM serially produced by Siemens  
resolution ca. 7 nm



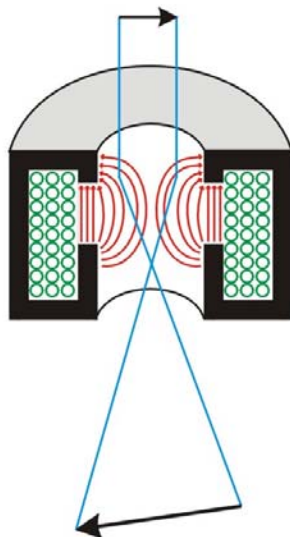
~1970: HRTEM  
Philips EM400, V = 120 kV  
resolution ca. 0.35 nm



~1990  
Philips CM30, V = 300 kV  
resolution ca. 0.2 nm

History of Electron Microscopy

## Magnetic Lens



An electron in a magnetic field (here: inhomogeneous, but axially symmetric) experiences the Lorentz force  $F$ :

$$F = -e (E + v \times B)$$

$$|F| = evB \sin(\nu, B)$$

$E$ : strength of electric field

$B$ : strength of magnetic field

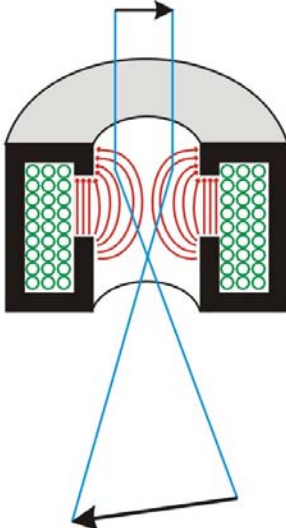
$e/v$ : charge/velocity of electrons

### Magnetic lenses

- manipulate the electron beam
- form an image of the object

Transmission Electron Microscopy

## Magnetic Lens



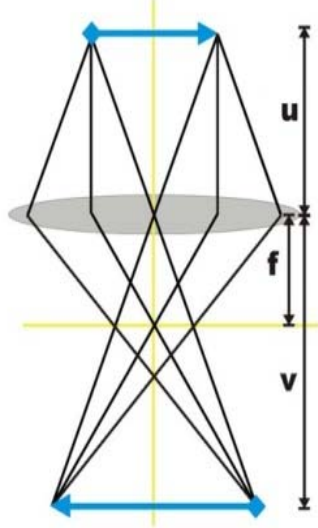
**Object plane**

**Lens**

**Back focal plane**

**Lens problems:**  
spherical aberation  $C_s$   
chromatic aberation  $C_c$   
astigmatism

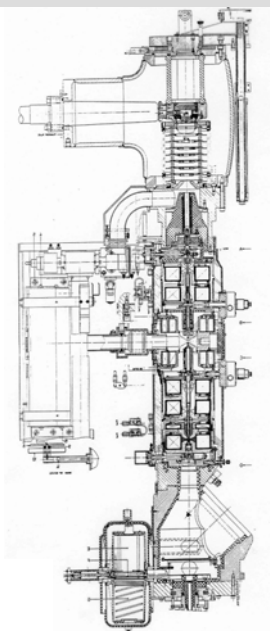

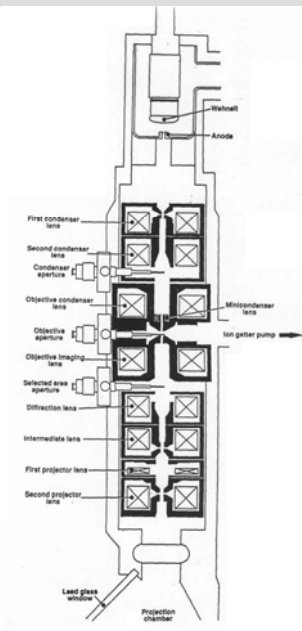
## Light optical analogue



Lens equation:  $1/u + 1/v = 1/f$   
Magnification  $M = v/u$

Transmission Electron Microscopy

## Cross-Section of the Column of a CM30 Microscope

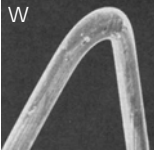
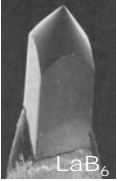




Transmission Electron Microscopy

## Electron Guns

**Thermoionic Guns**

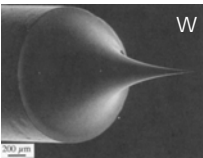
Electron emission by heating

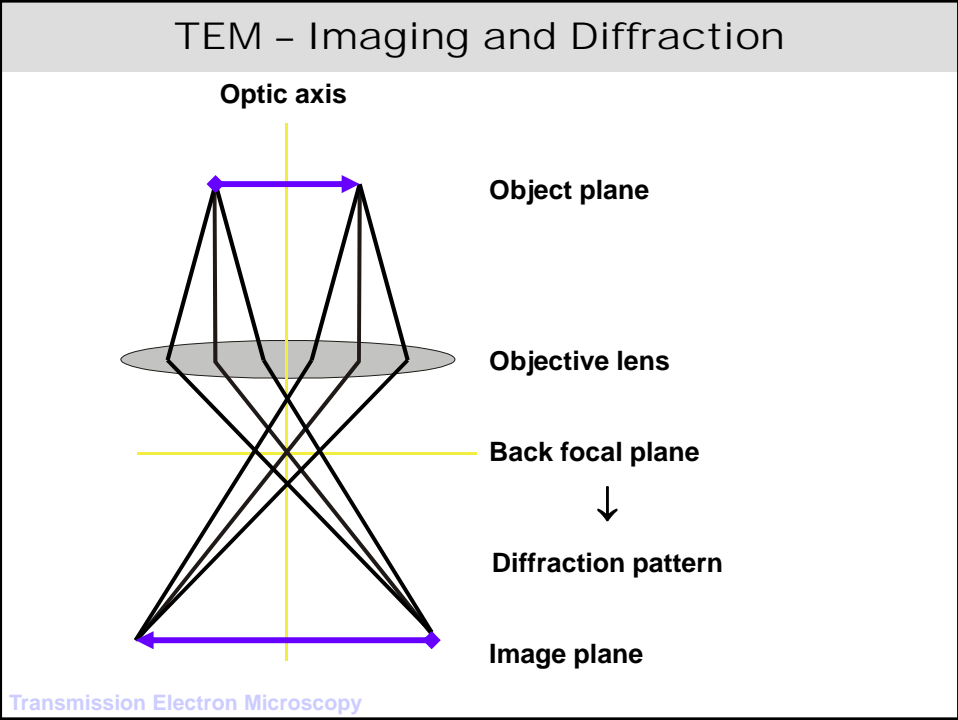
Properties	W	LaB <sub>6</sub>	FEG
Work function / eV	4.5	2.4	4.5
Temperature / K	2700	2000	(300-)1800
Energy spread / eV	3-4	1.5-3	0.4-1.5
Source size / nm	30000	5000	3-20
Maximum current / nA	1000	500	(30-)300
Brightness / A/m <sup>2</sup> sr	10 <sup>9</sup>	5x10 <sup>10</sup>	10 <sup>13</sup>
Lifetime / h	100	500	>1000

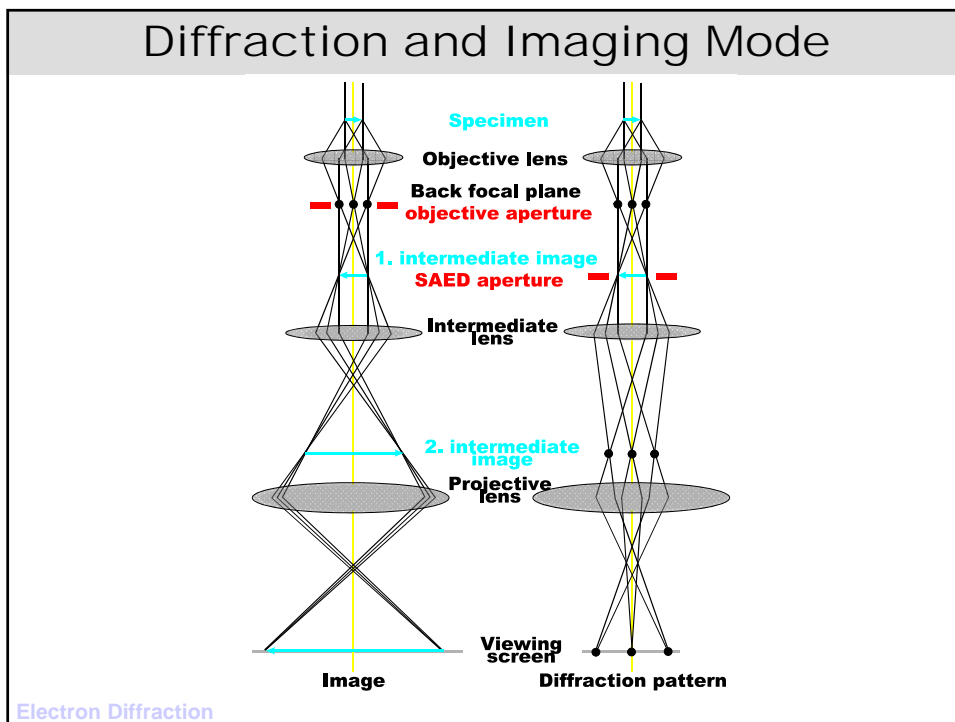
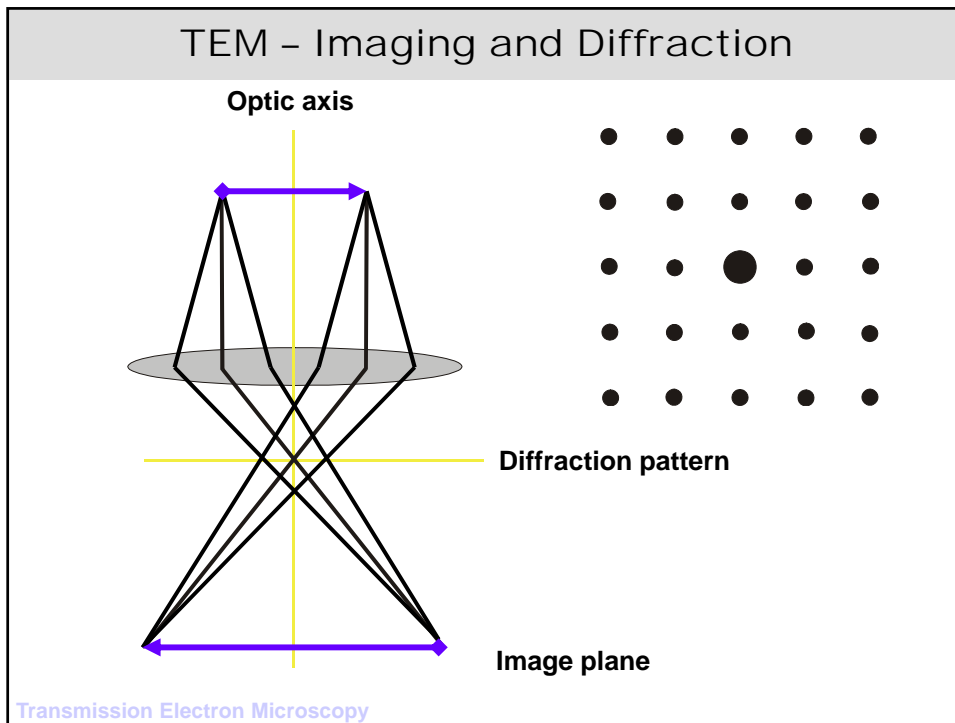
**Field Emission Guns (FEG)**

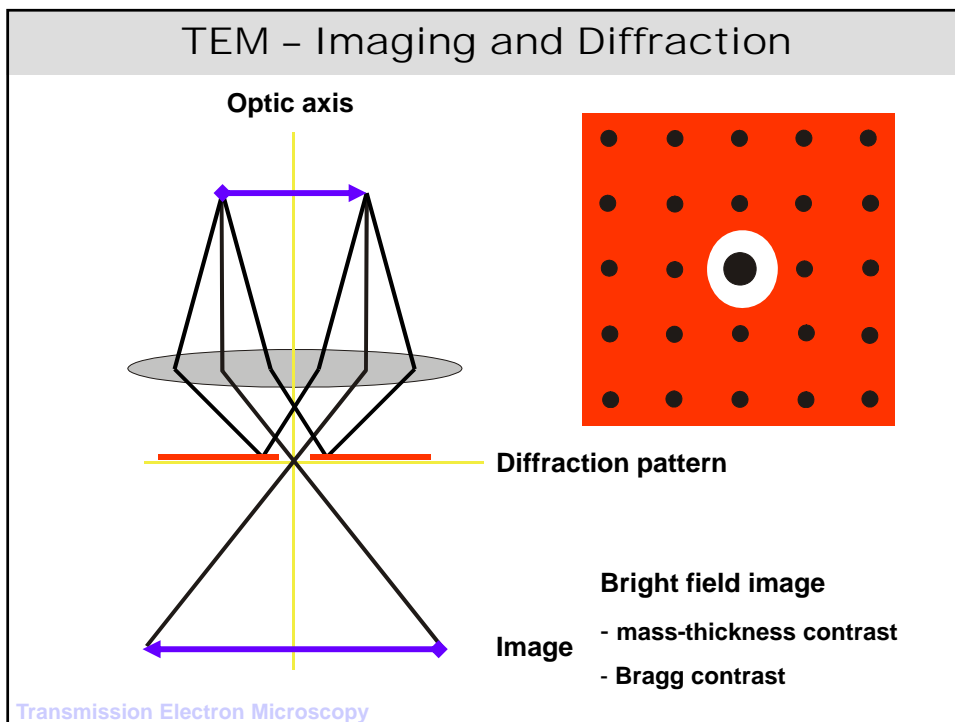
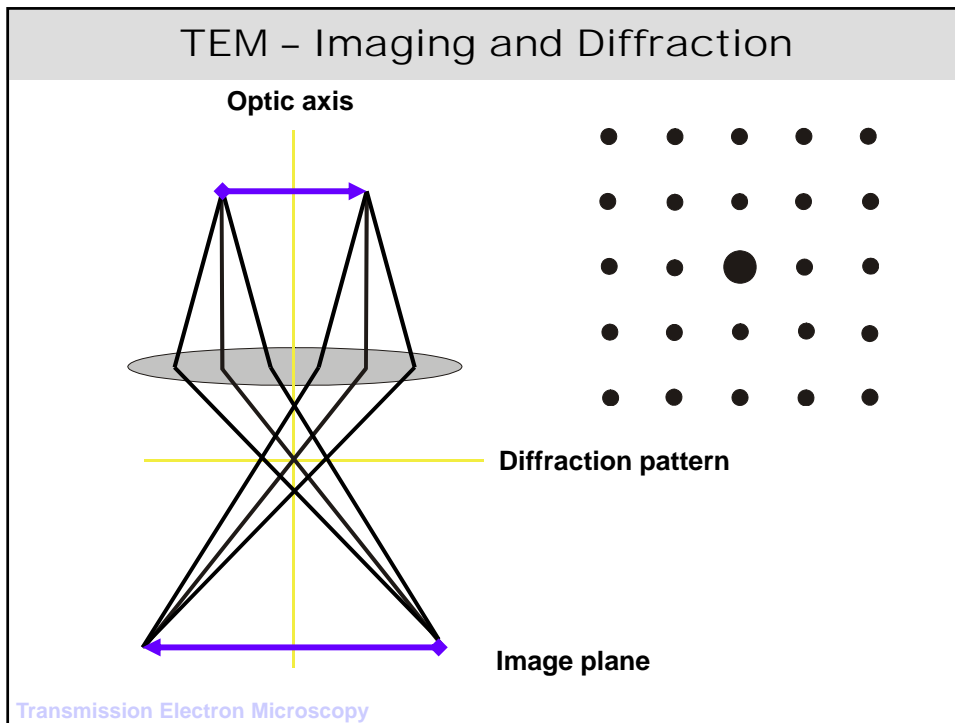
Electron emission by applying an extraction voltage

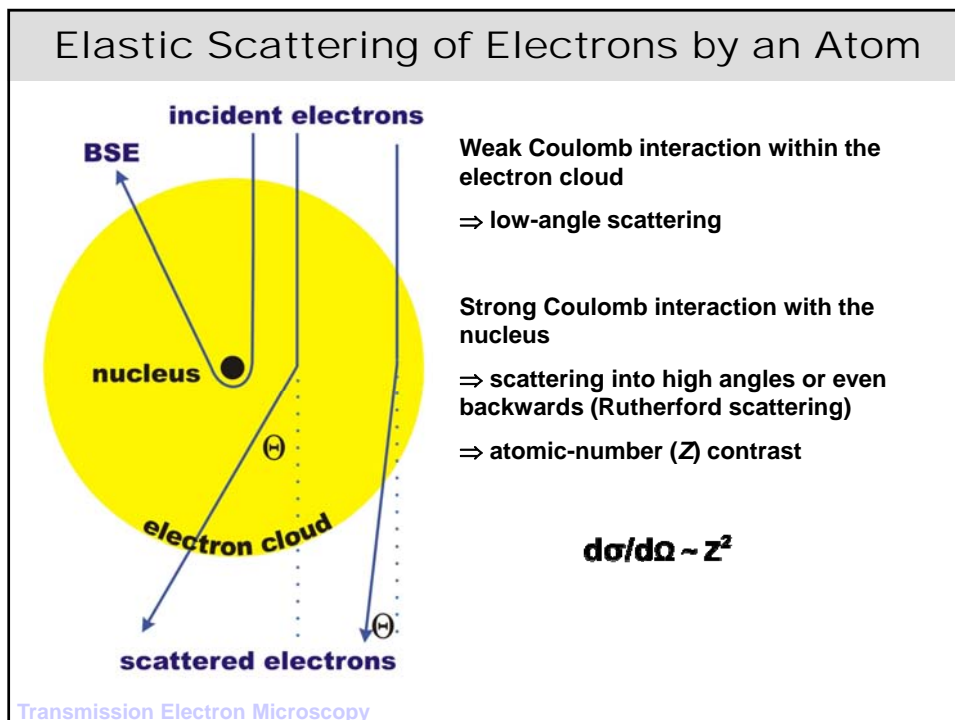
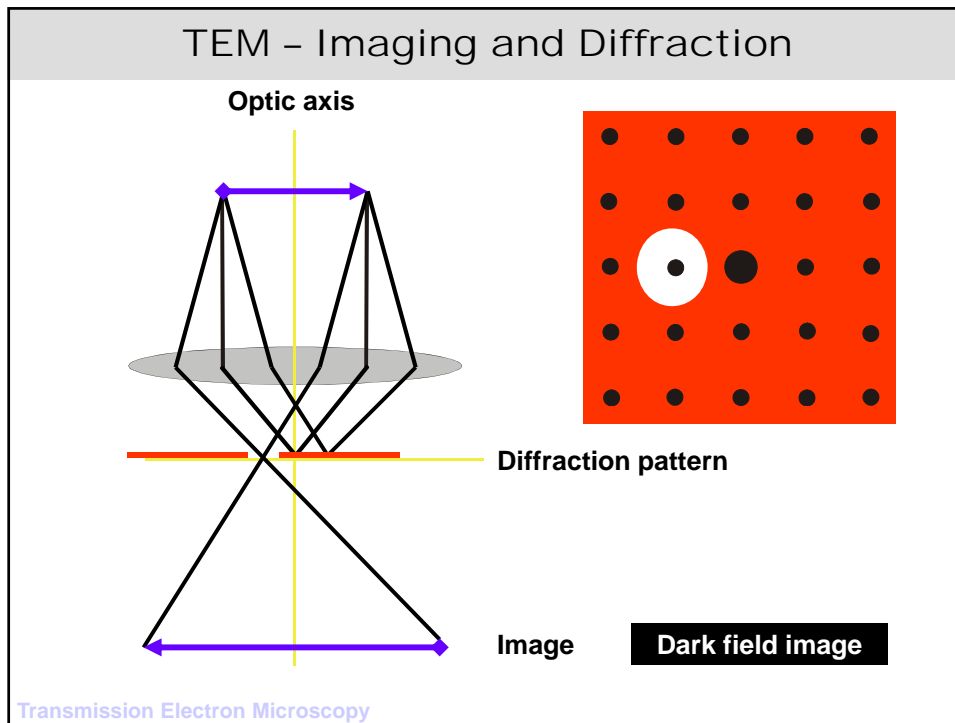


Transmission Electron Microscopy

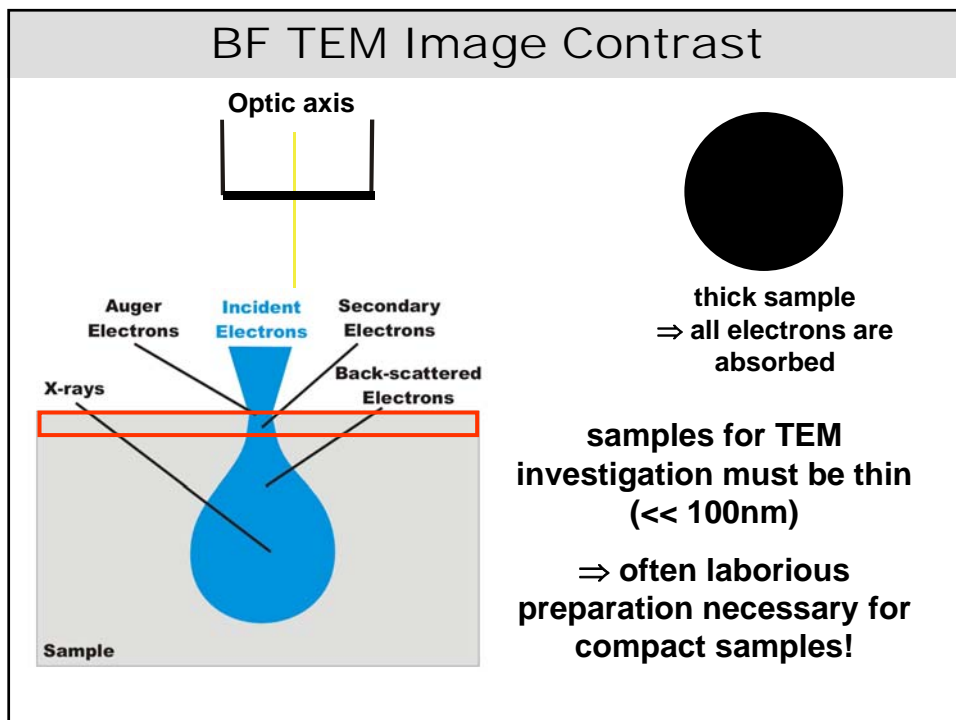
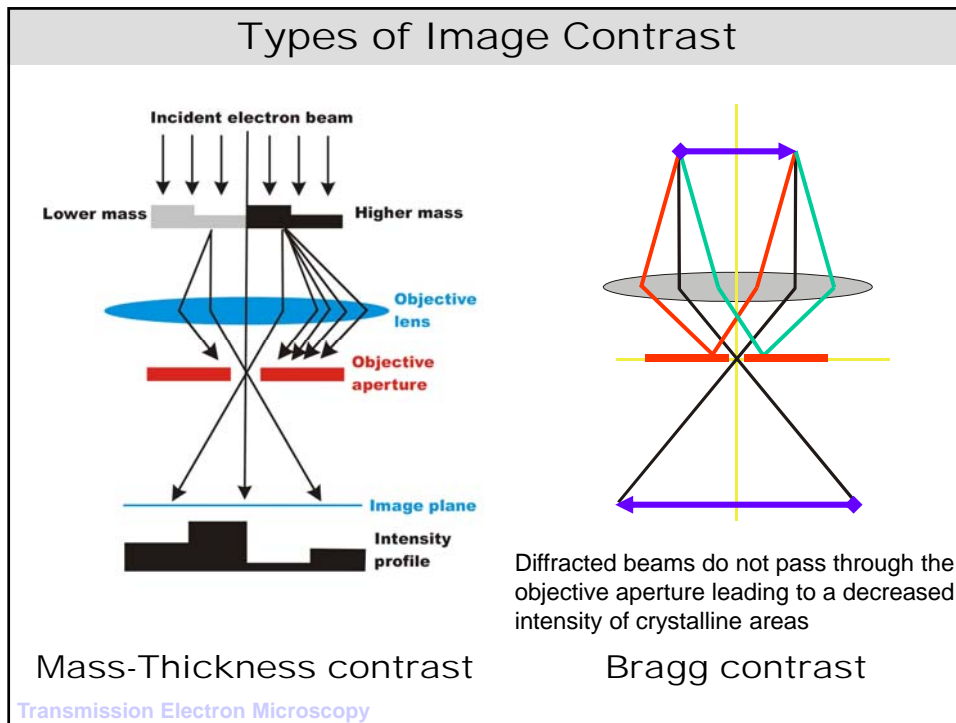


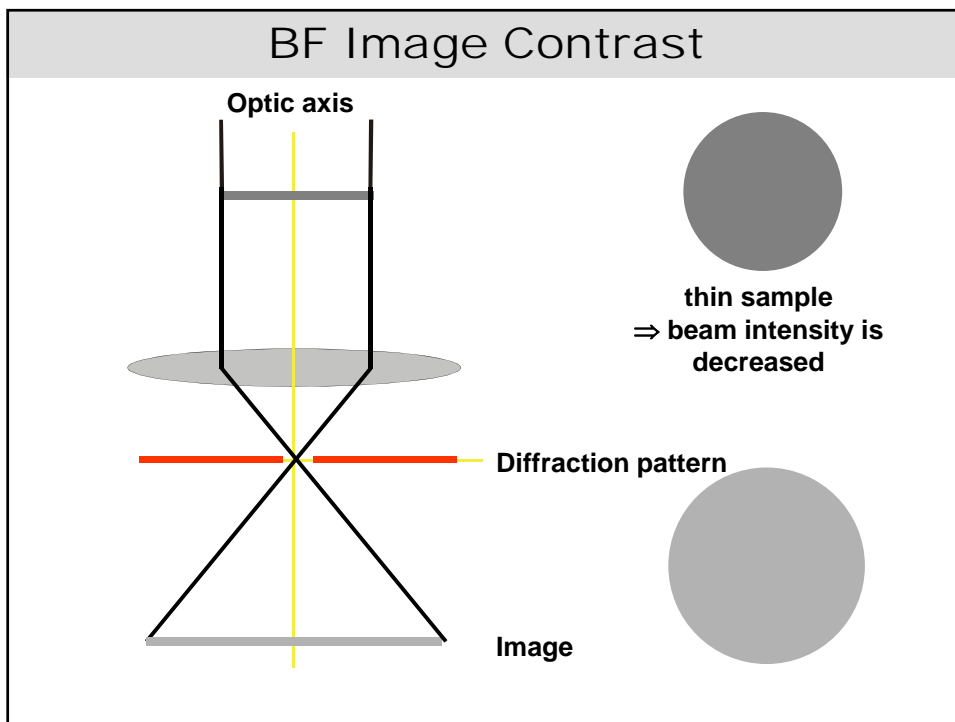
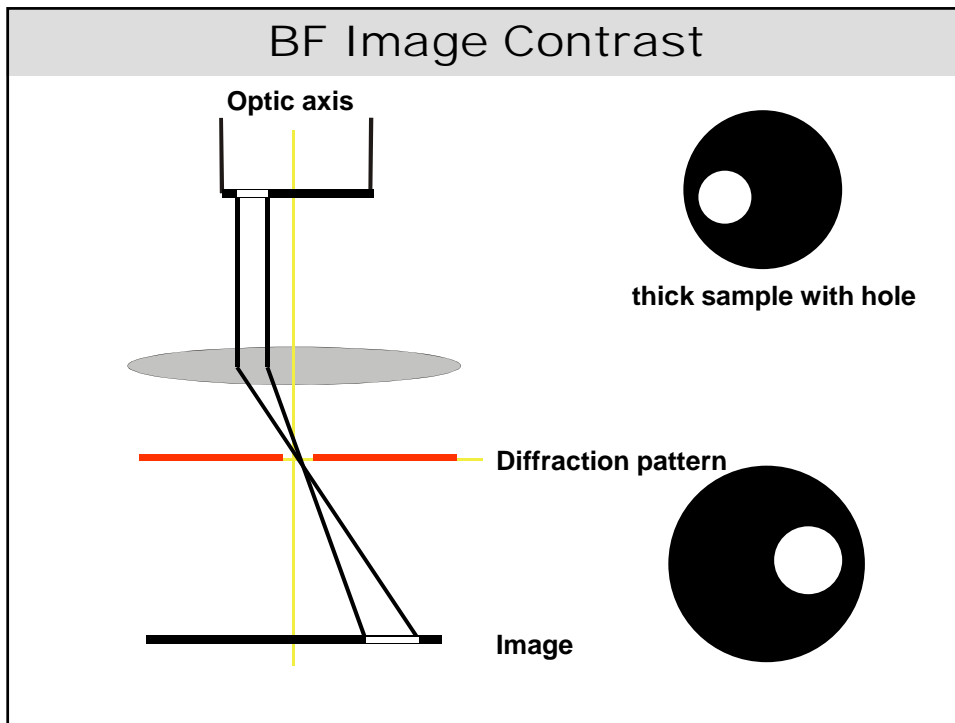


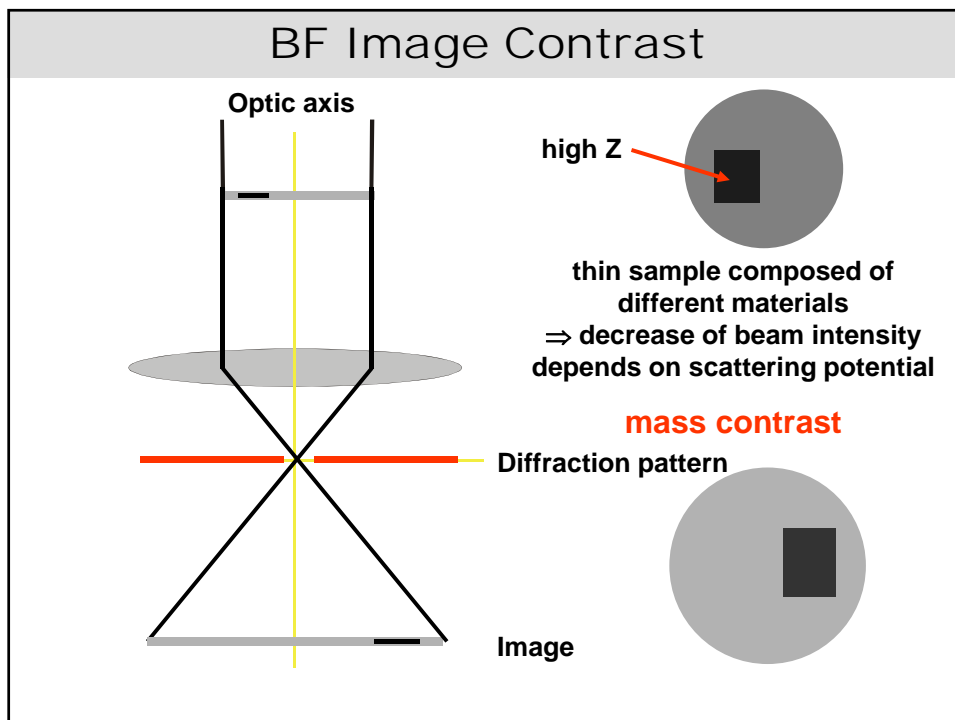
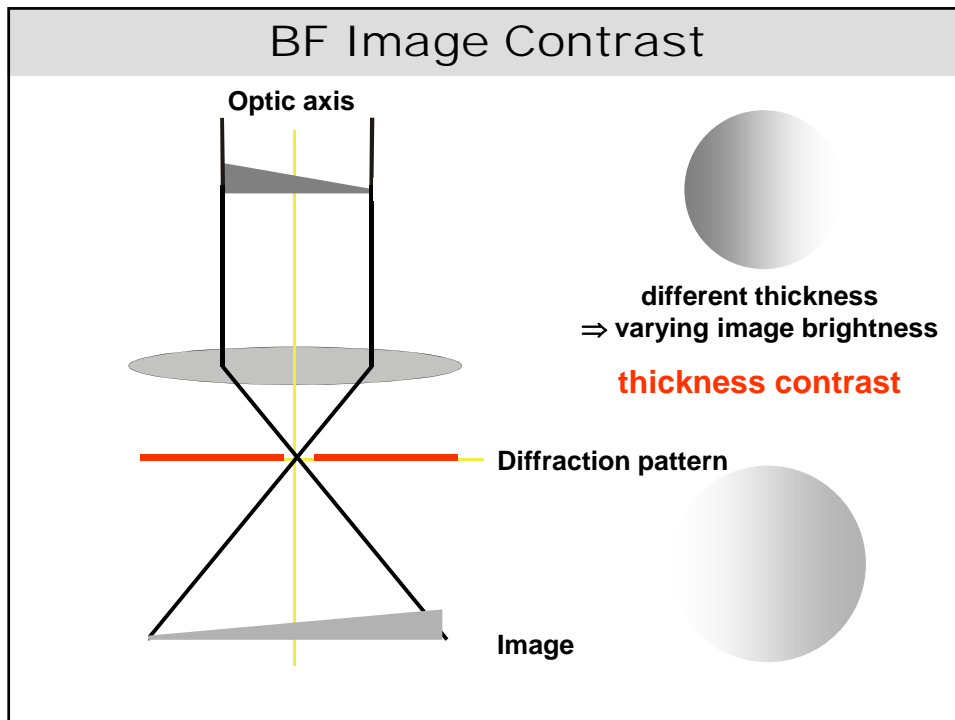




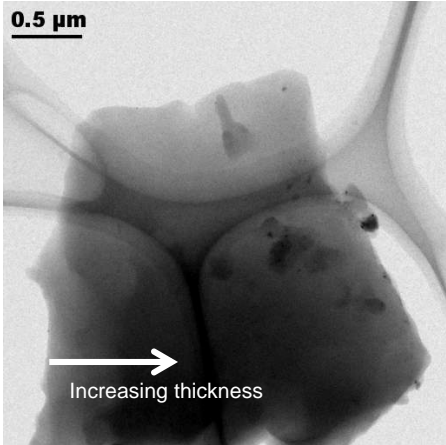








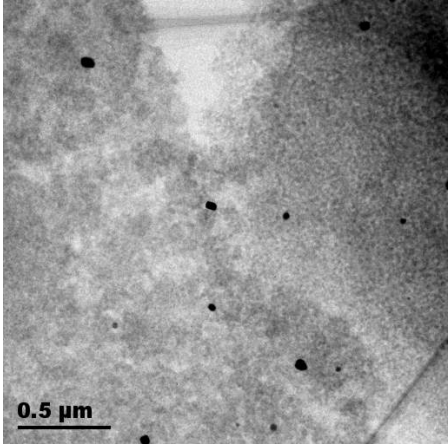
### BF Images



**0.5 μm**

Increasing thickness

Amorphous SiO<sub>2</sub> on C foil  
**Mainly thickness contrast**

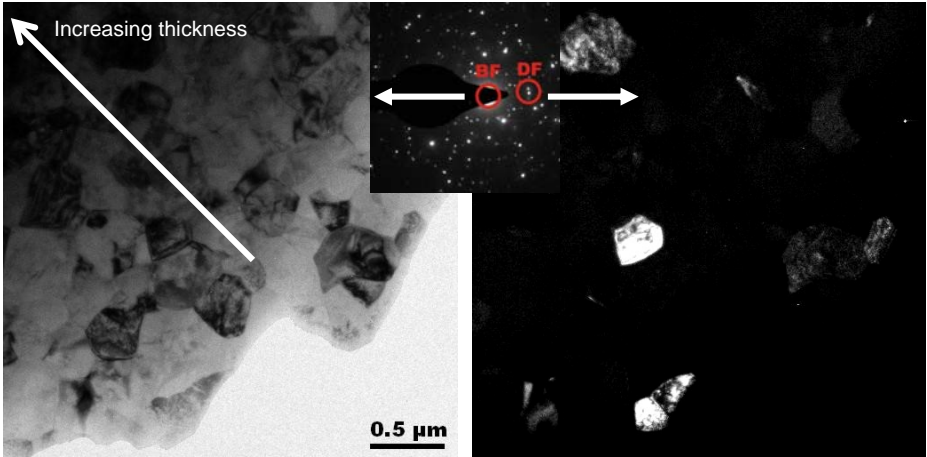


**0.5 μm**

Au particles (black) on TiO<sub>2</sub>  
**Mainly mass contrast**

Transmission Electron Microscopy

### BF and DF Images

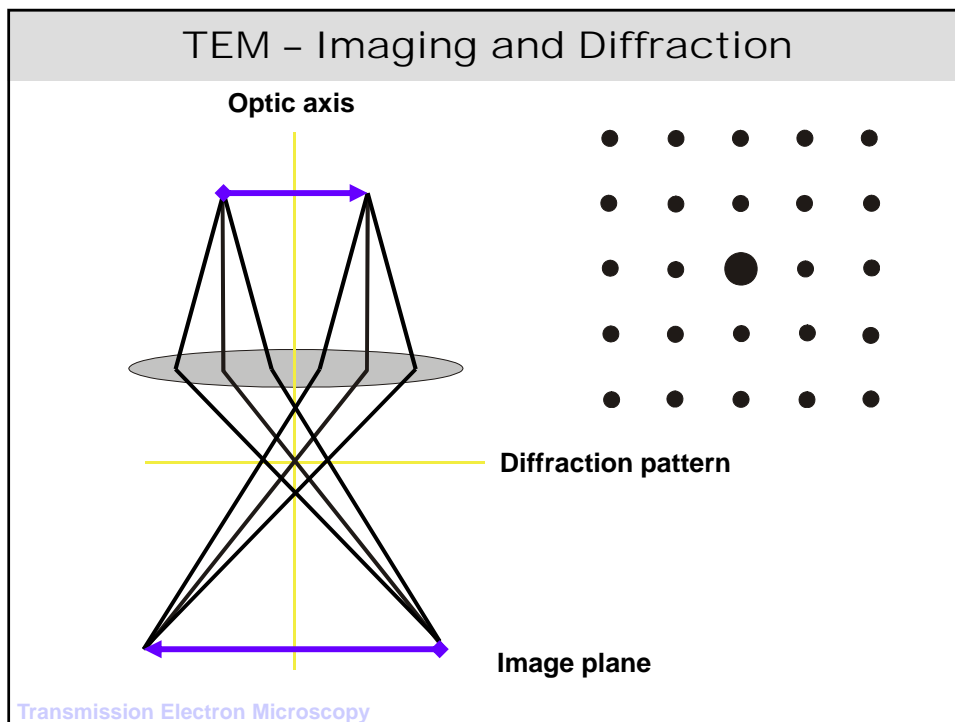
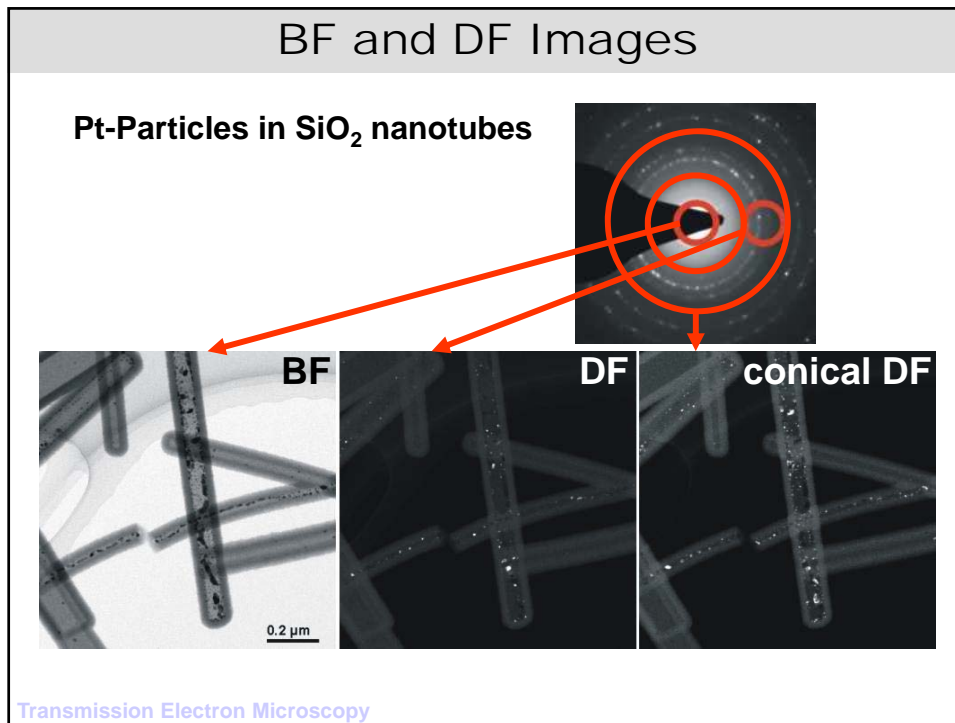


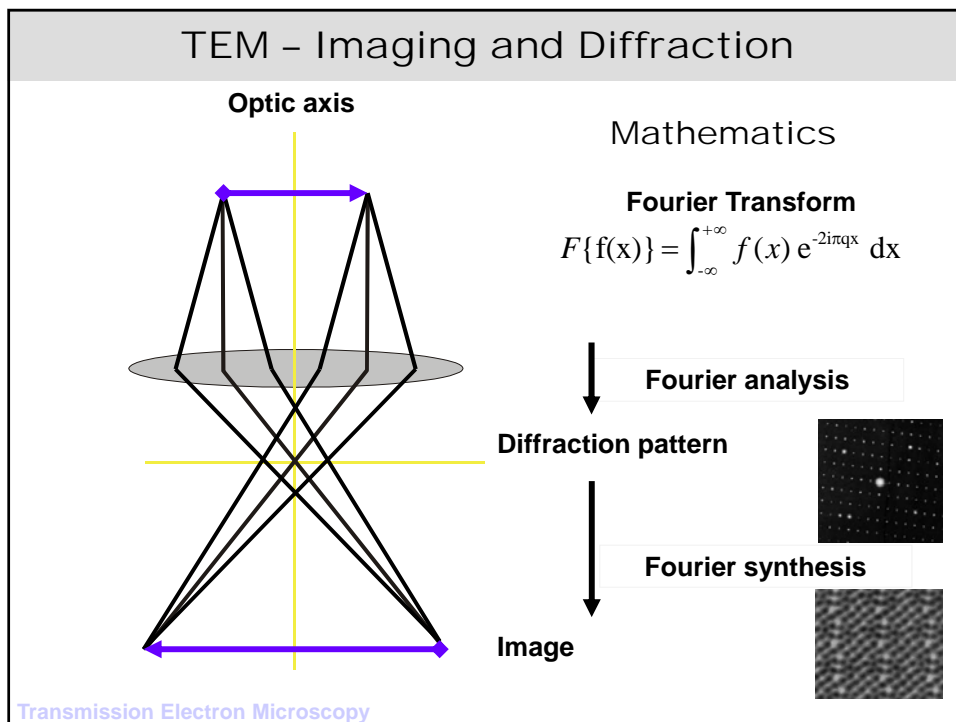
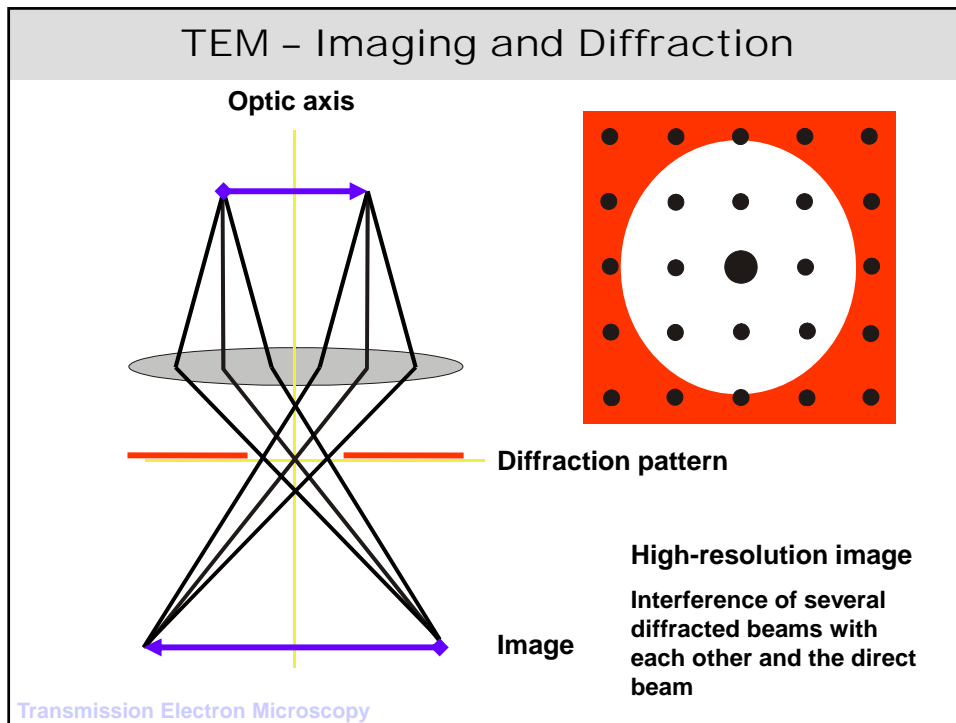
Increasing thickness

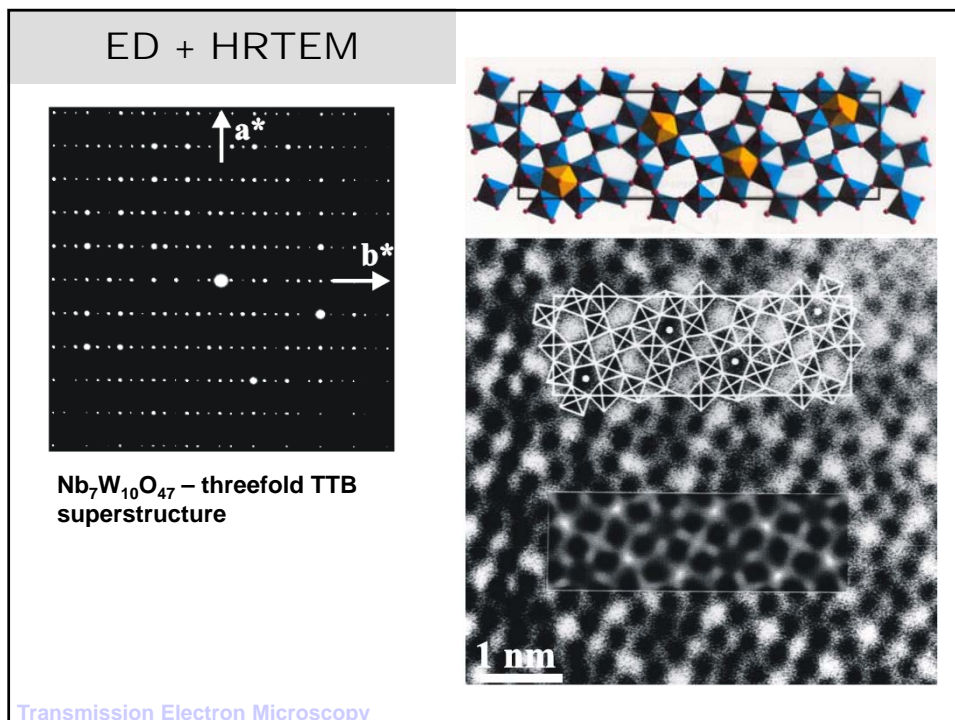
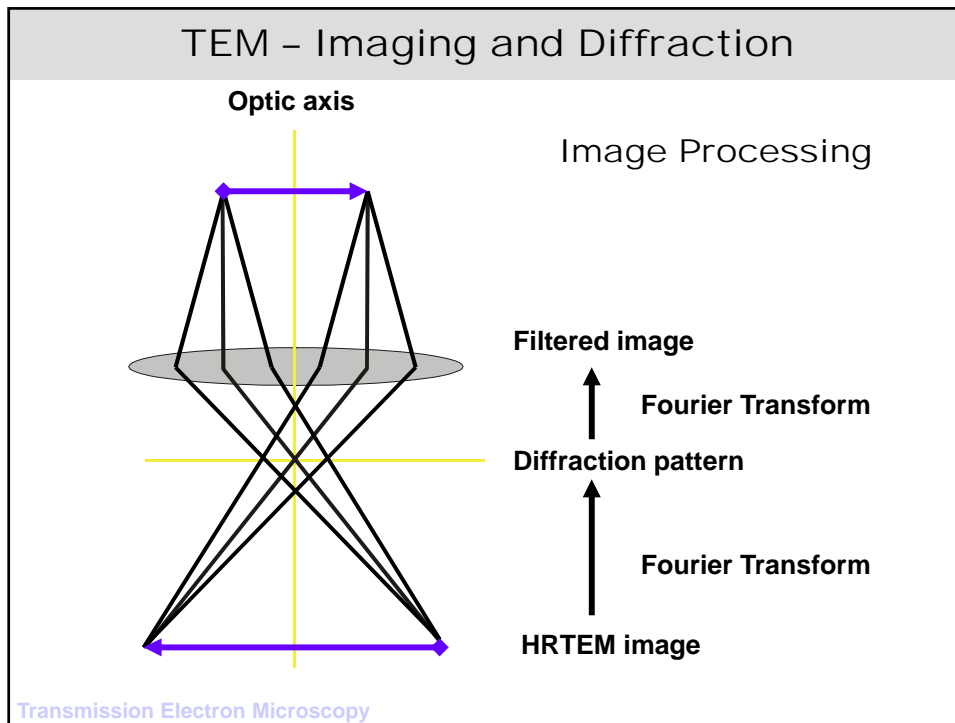
**0.5 μm**

ZrO<sub>2</sub> micro crystals; crystals orientated close to a zone axis appear dark in BF and bright in DF  
**Mainly Bragg contrast**

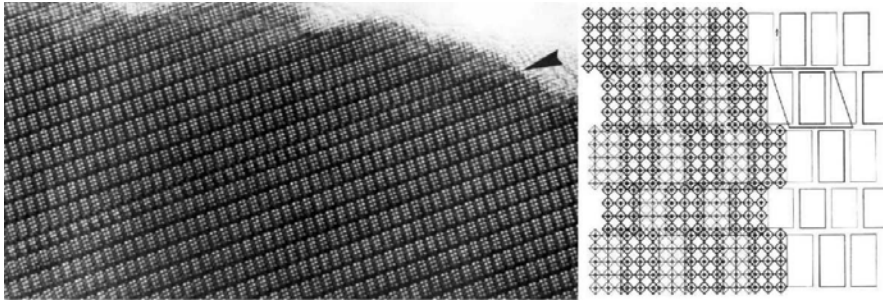
Transmission Electron Microscopy







## HRTEM: Detection of Defects

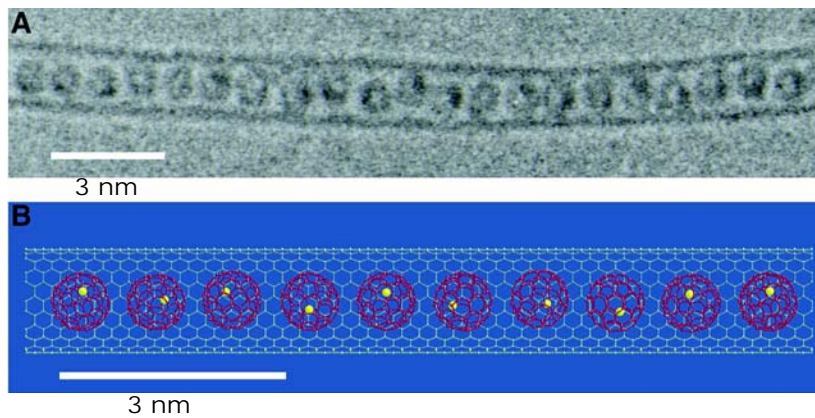


Planar defect in  $\text{ZnNb}_{14}\text{O}_{35}\text{F}_2$

Transmission Electron Microscopy

## HRTEM: Imaging Single Atoms

$\text{Gd}@C_{82}$  in SWCNT



Transmission Electron Microscopy

Suenaga et al, *Science* **290** (2000) 2280



## Projection Problem: 3D $\Rightarrow$ 2D



Transmission Electron Microscopy

From: Williams, Carter: Transmission Electron Microscopy

## Transmission Electron Microscopy

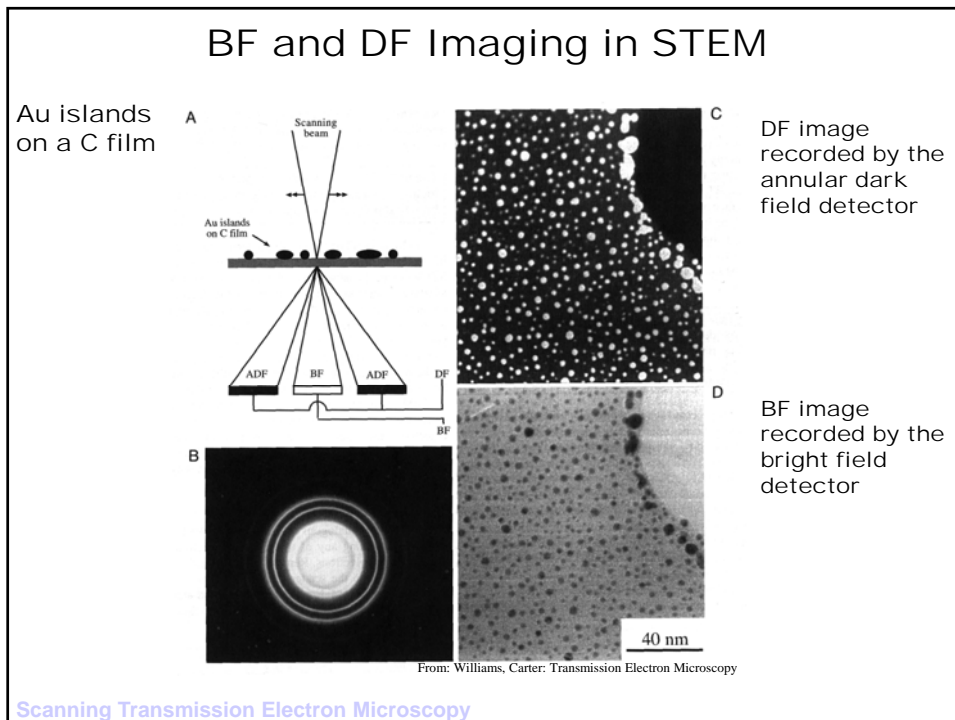
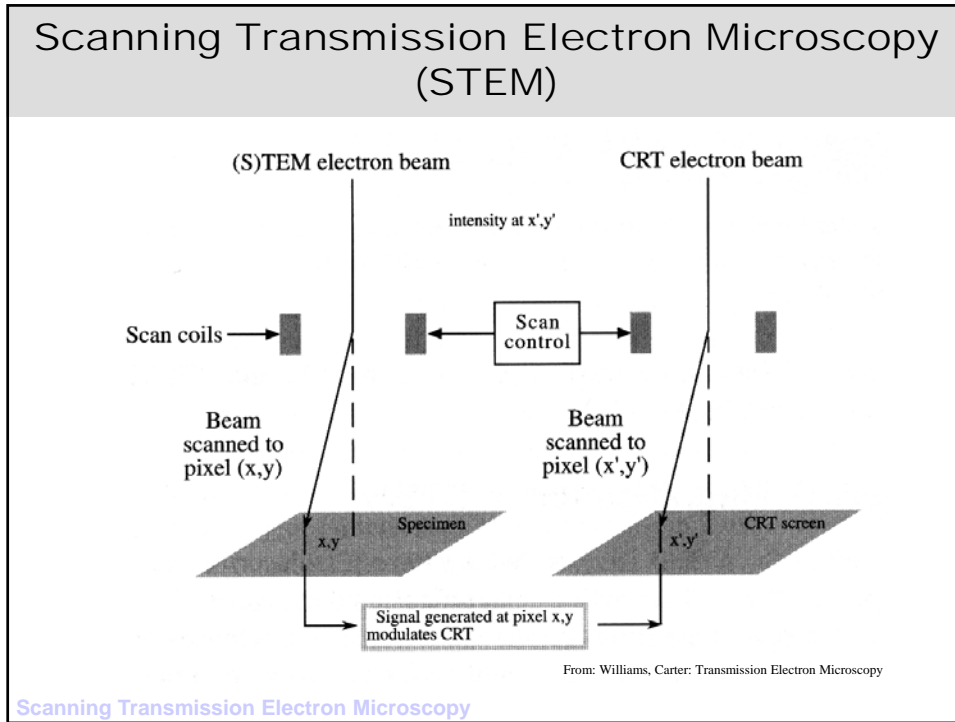
### Types of contrast:

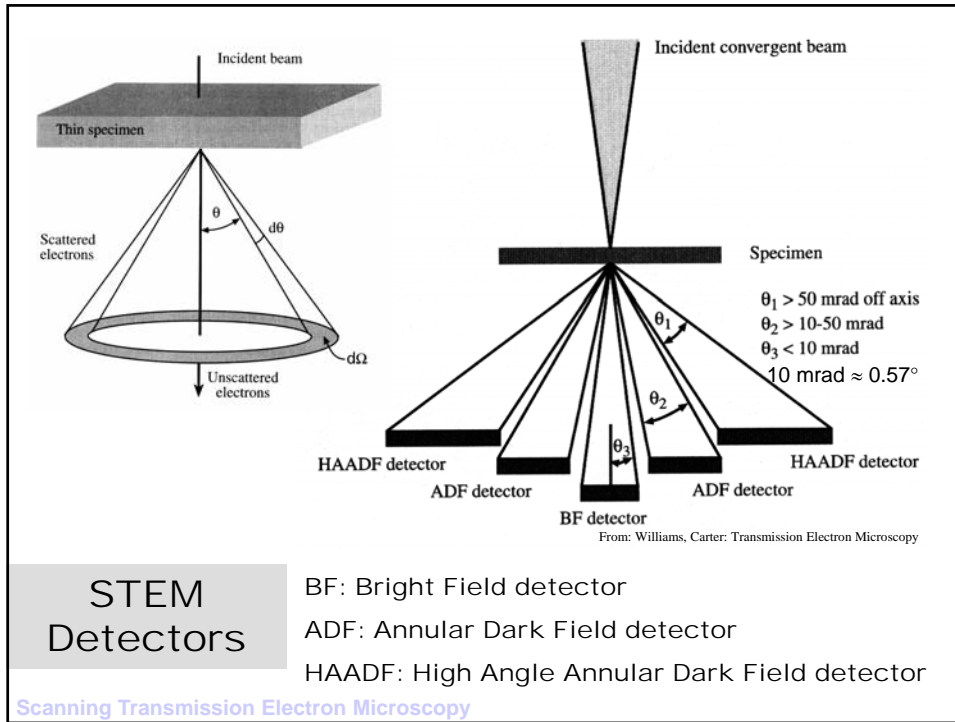
- Mass-thickness (BF/DF)
- Bragg (BF/DF)
- Phase (HRTEM; resolution limit  $< 1\text{\AA}$ )

### Determination of

- Structure: HRTEM
- Defects: HRTEM, TEM
- Lattice constants and symmetry: ED
- Particle size: TEM, HRTEM

Transmission Electron Microscopy

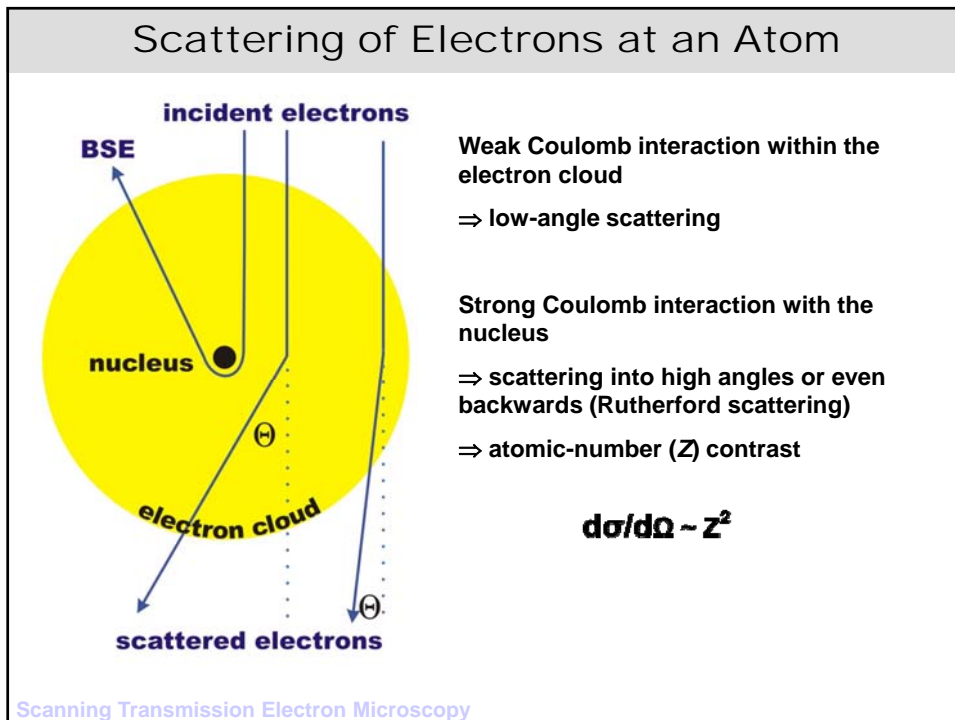




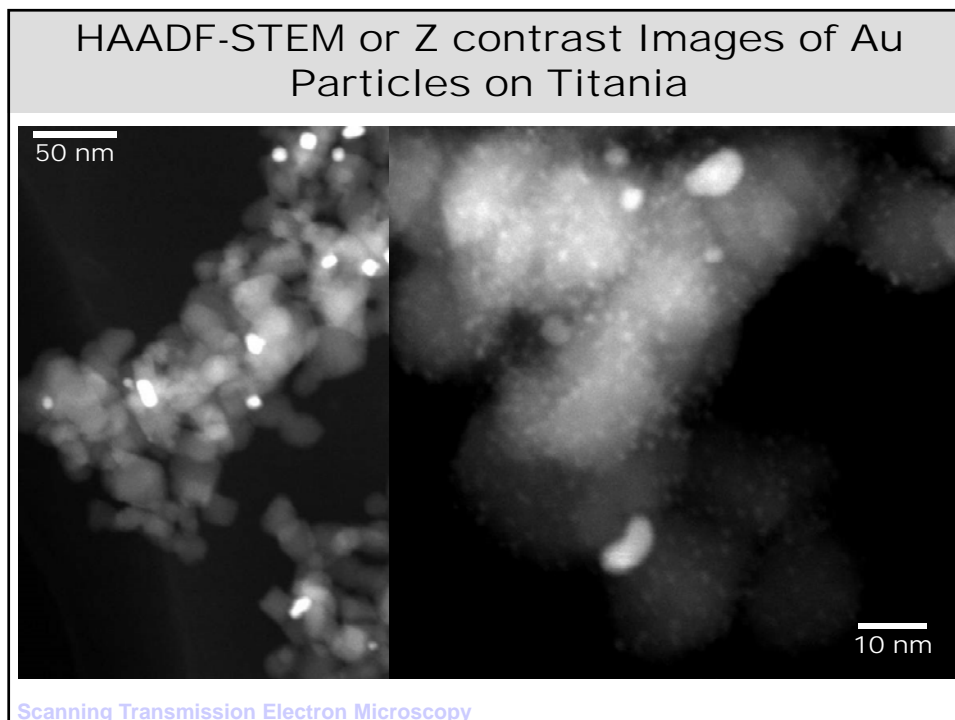
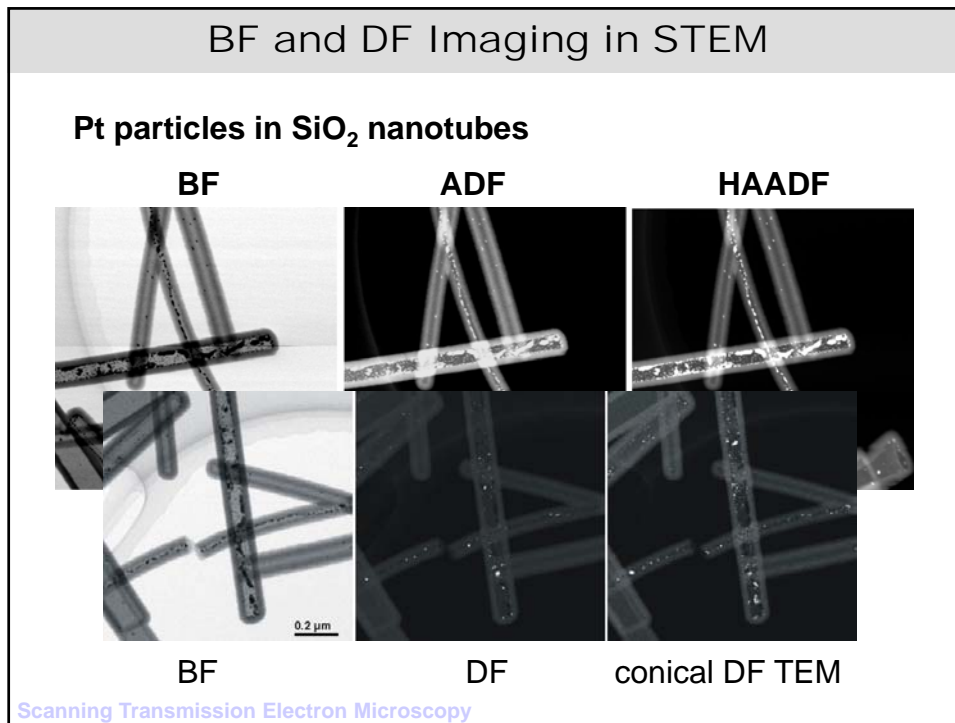
**STEM Detectors**

BF: Bright Field detector  
 ADF: Annular Dark Field detector  
 HAADF: High Angle Annular Dark Field detector

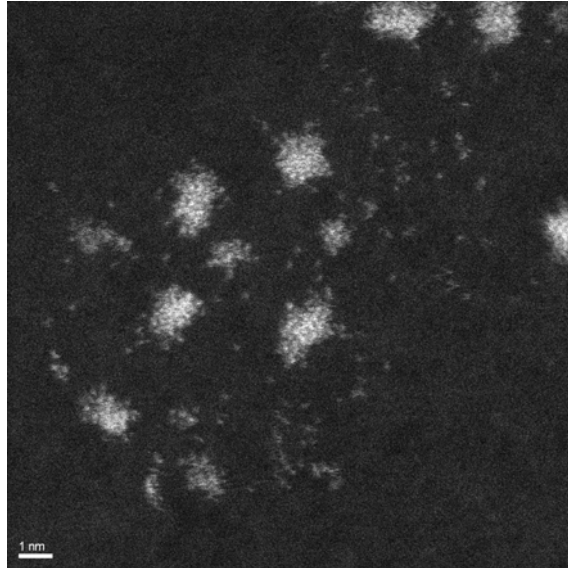
Scanning Transmission Electron Microscopy



Scanning Transmission Electron Microscopy

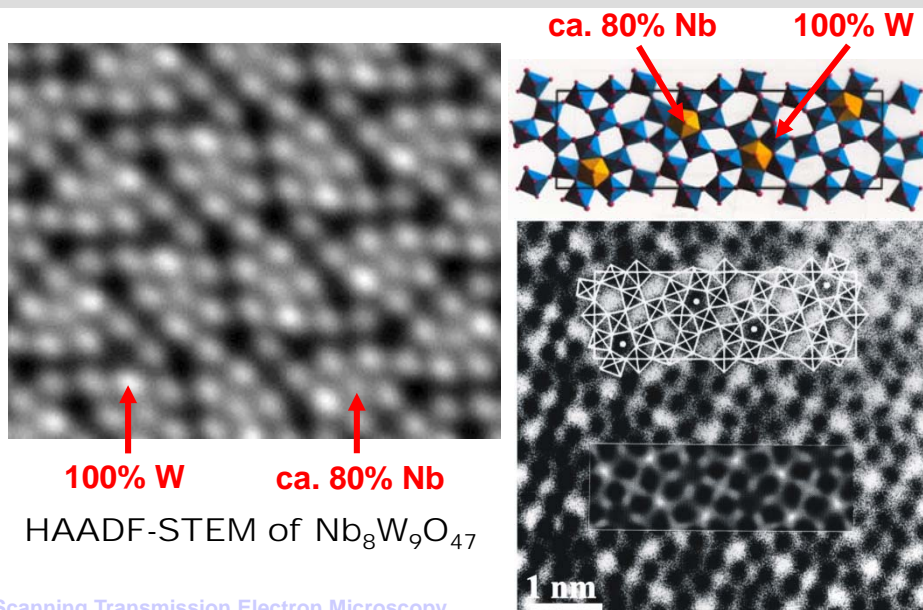


## HAADF-STEM or Z contrast Images of Pt Clusters and Atoms on Carbon



Scanning Transmission Electron Microscopy

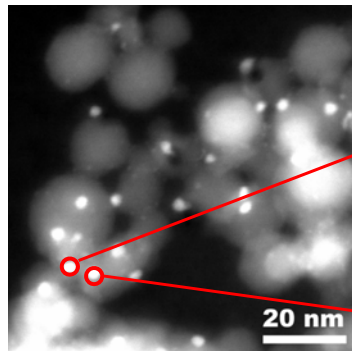
## Information about Elemental Distribution in HAADF-STEM or Z contrast images



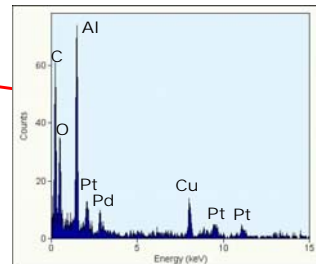
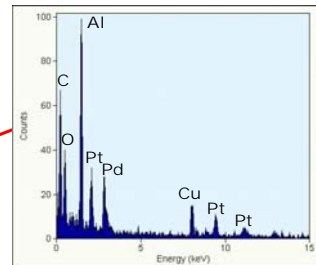
Scanning Transmission Electron Microscopy

## Pd and Pt supported on alumina: Size of the particles? Alloy or separated?

STEM + EDXS: Point Analyses



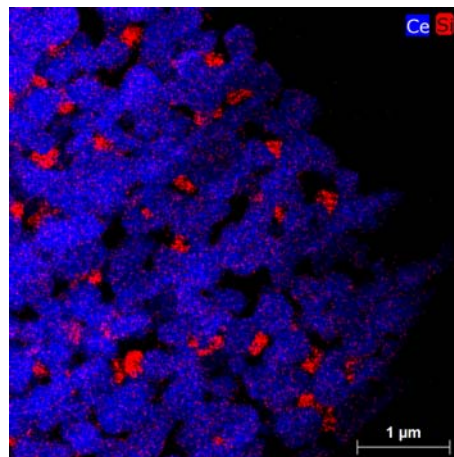
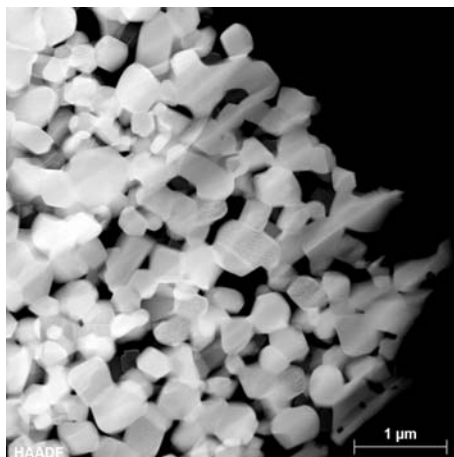
HAADF-STEM image



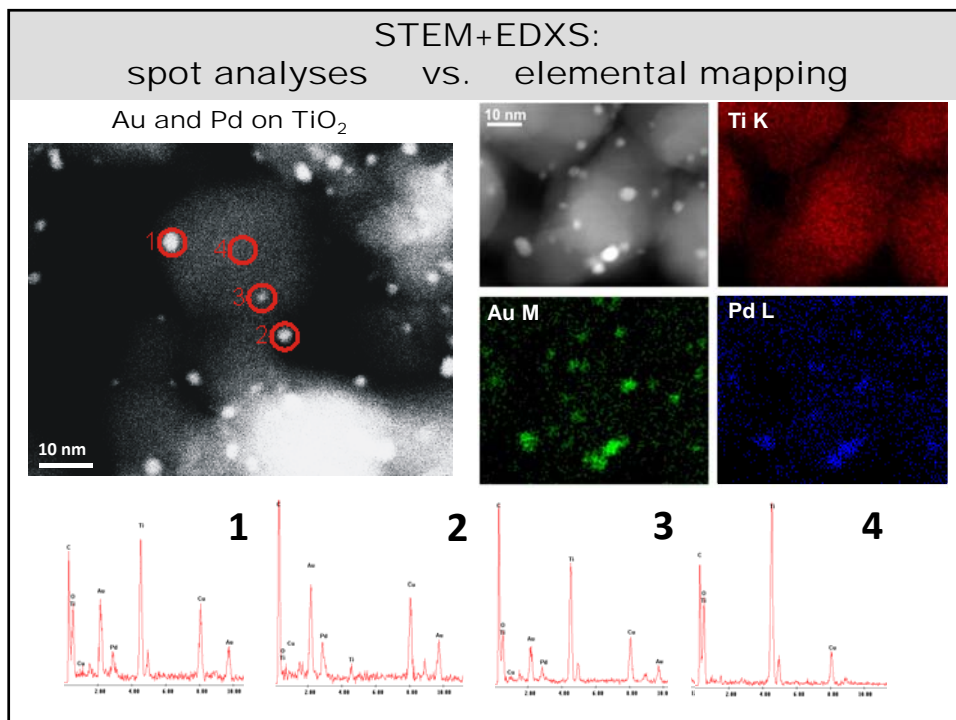
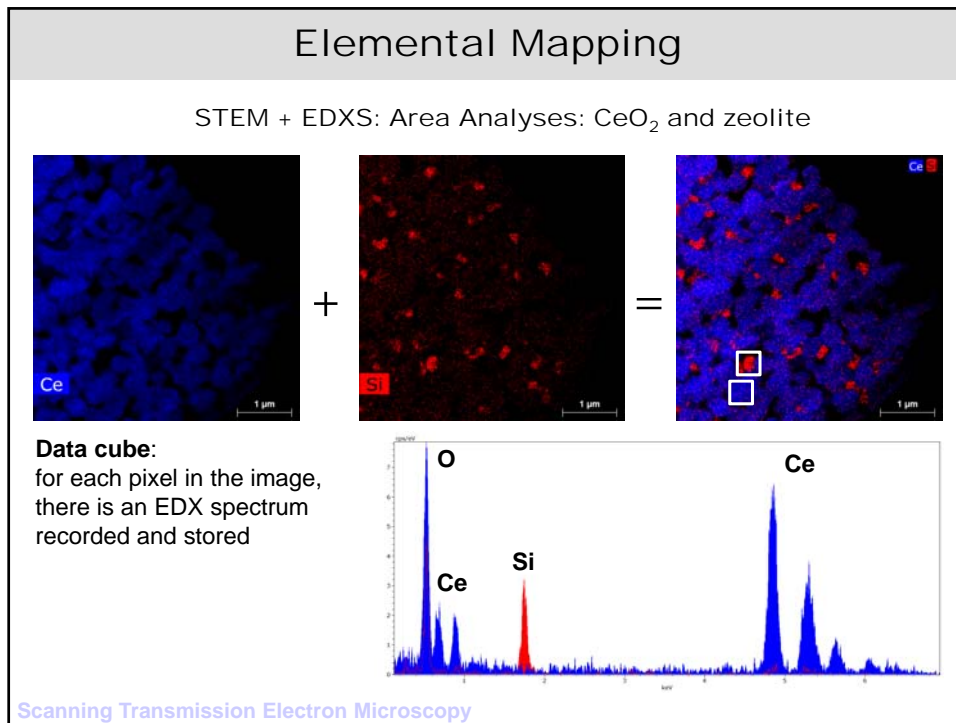
Scanning Transmission Electron Microscopy

## Elemental Mapping

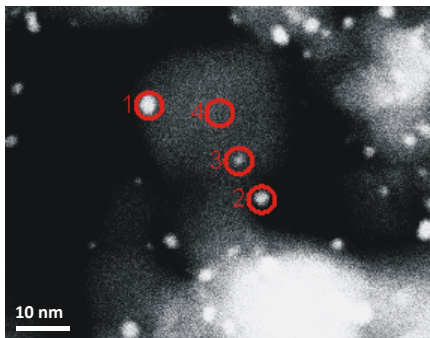
STEM + EDXS: Area Analyses: CeO<sub>2</sub> and zeolite



Scanning Transmission Electron Microscopy

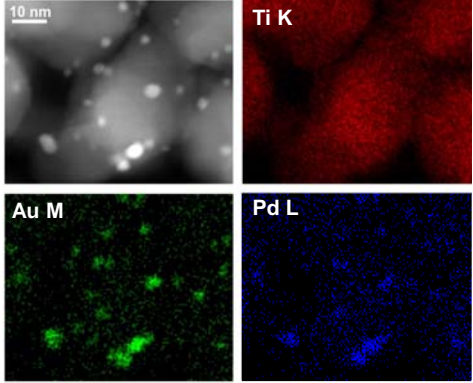


**STEM+EDXS:**  
spot analyses vs. elemental mapping



**quick and efficient if a clear contrast between the different components appears in STEM**

**EDX spectra of selected spots with good signal:noise ratio measured in < 1 min**



**time-consuming but provides the full data cube (1EDXS/pixel)**

**EDX spectra extracted from selected spots with bad signal:noise ratio**

## Scanning Transmission Electron Microscopy

**Contrast:**

- Mass-thickness (BF/DF)
- Bragg (BF/DF)
- $Z^2$  (HAADF)

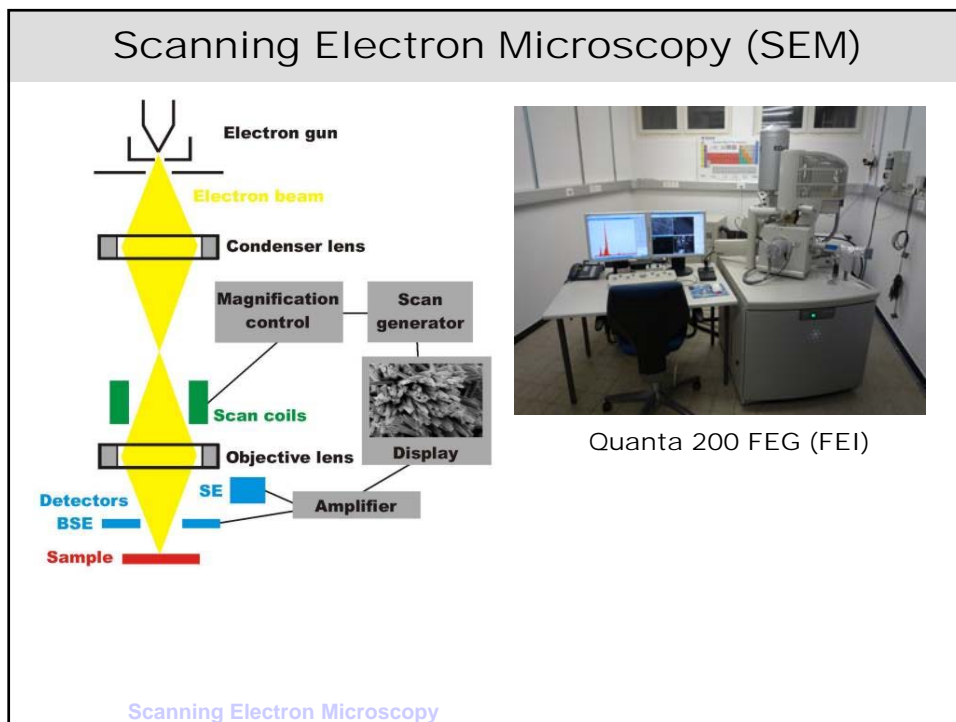
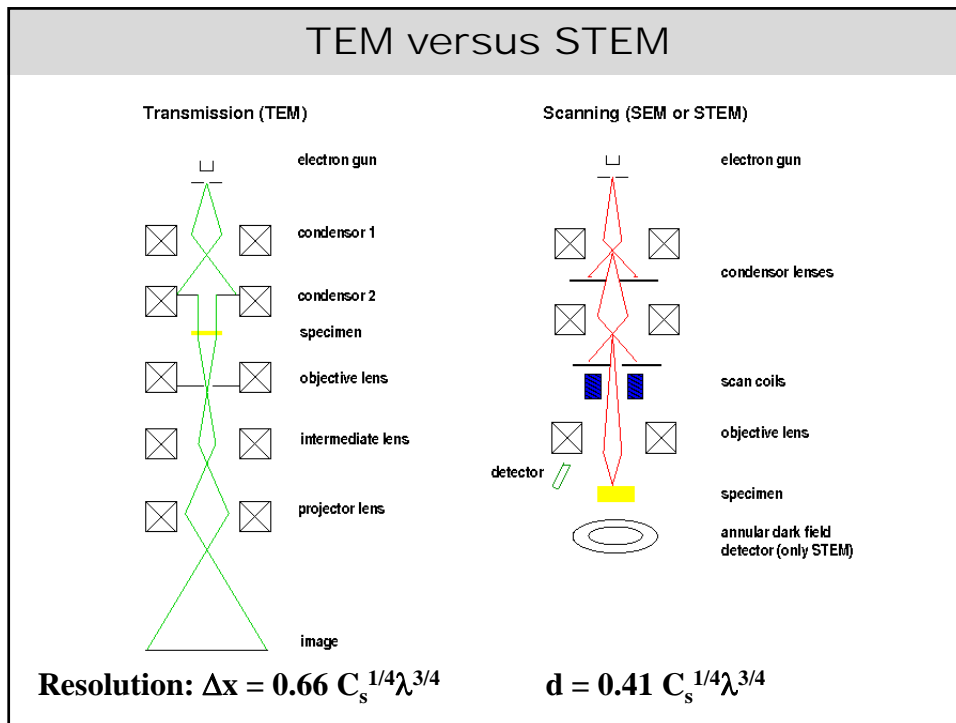
**Determination of**

- Particles on support : HAADF
- Structure and defects : HR
- Chemical information : HAADF

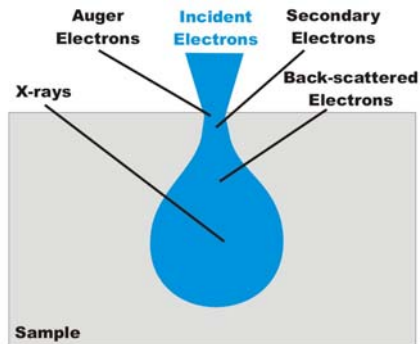
**Important: Combination with EDXS or EELS**

Scanning Transmission Electron Microscopy





## Signals used in the SEM



### Secondary Electrons (SE)

- low energy  $< 100$  eV (result of inelastic interactions)
- information about topography and morphology
- escape only when generated close to the surface

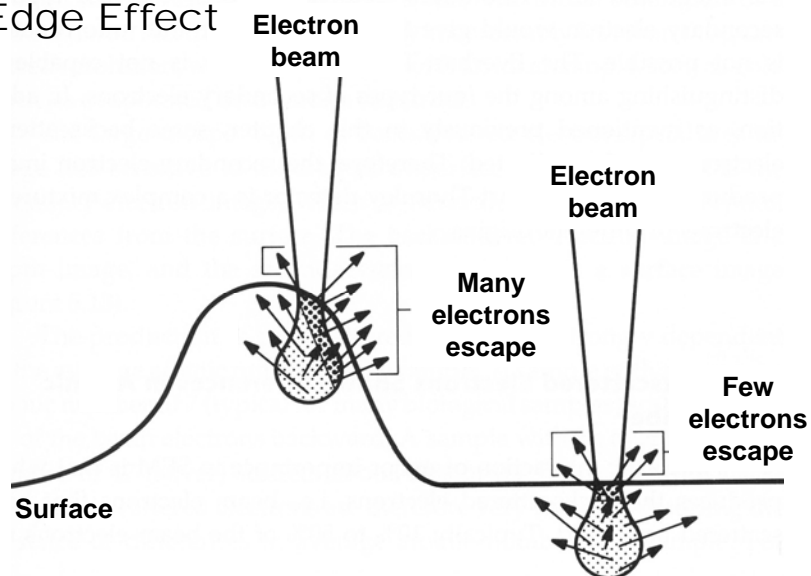
### Back-scattered Electrons (BSE)

- high energy  $\cong E_0$  (result of elastic interactions)
- morphology and chemical information

Scanning Electron Microscopy

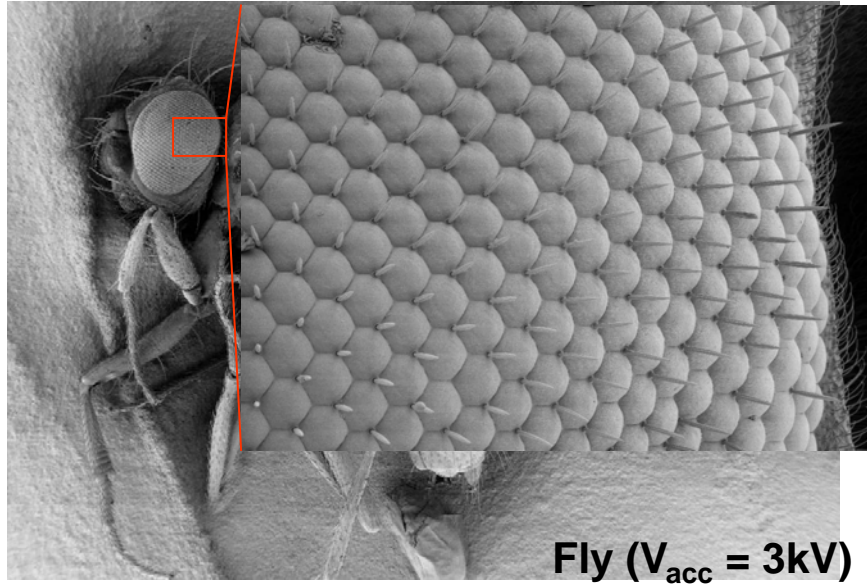
## Topographic Contrast in the SEM

### Edge Effect



Scanning Electron Microscopy

## SEM: Imaging with Secondary Electrons

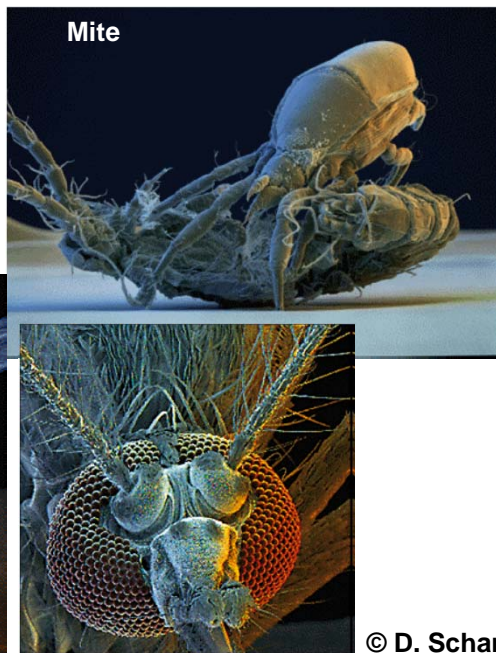


Scanning Electron Microscopy

## Colorized SEM Images

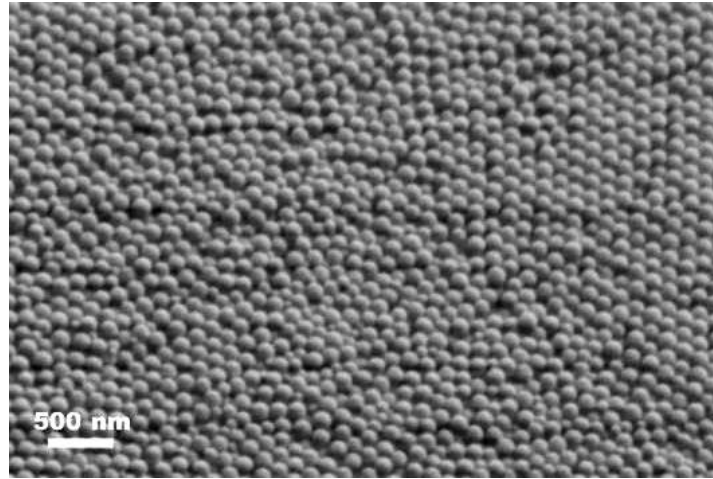


Scanning Electron Microscopy



© D. Scharf  
www.scharfphoto.com

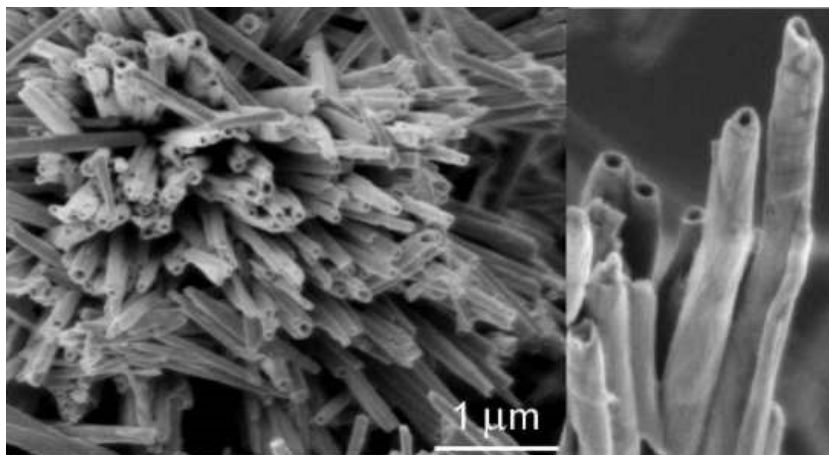
## SEM: Imaging with Secondary Electrons



**Latex balls ( $V_{acc} = 1\text{kV}$ )**

Scanning Electron Microscopy

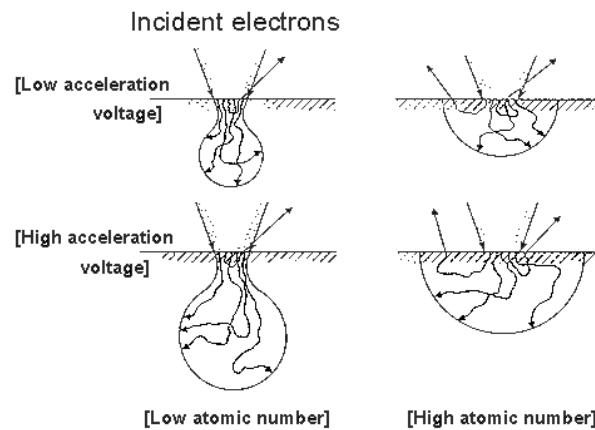
## SEM: Imaging with Secondary Electrons



**Vanadium oxide nanotubes ( $V_{acc} = 1\text{kV}$ )**

Scanning Electron Microscopy

## SEM: Dependence on Electron Energy



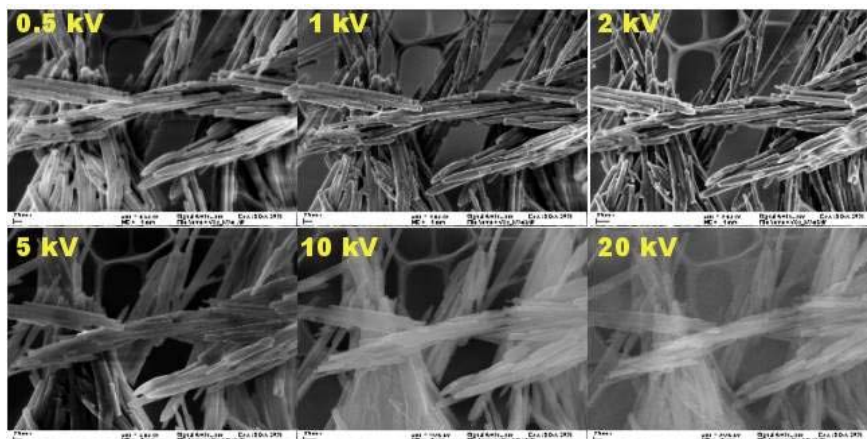
## Penetration depth of electrons in matter

➤ increases with increasing  $V_{acc}$

➤ decreases with increasing atomic number

Scanning Electron Microscopy

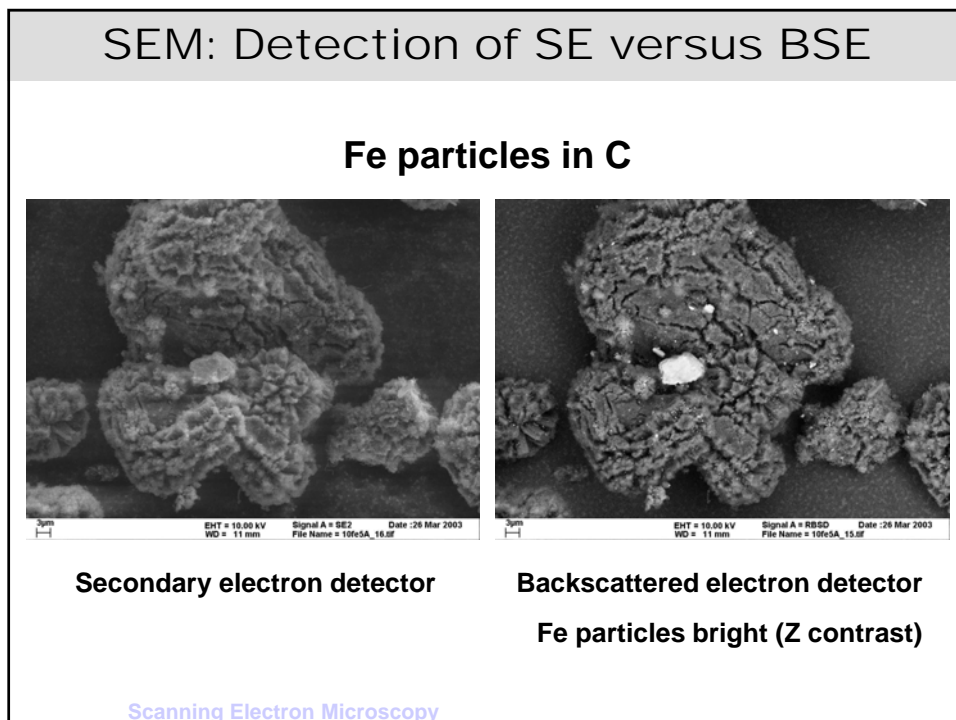
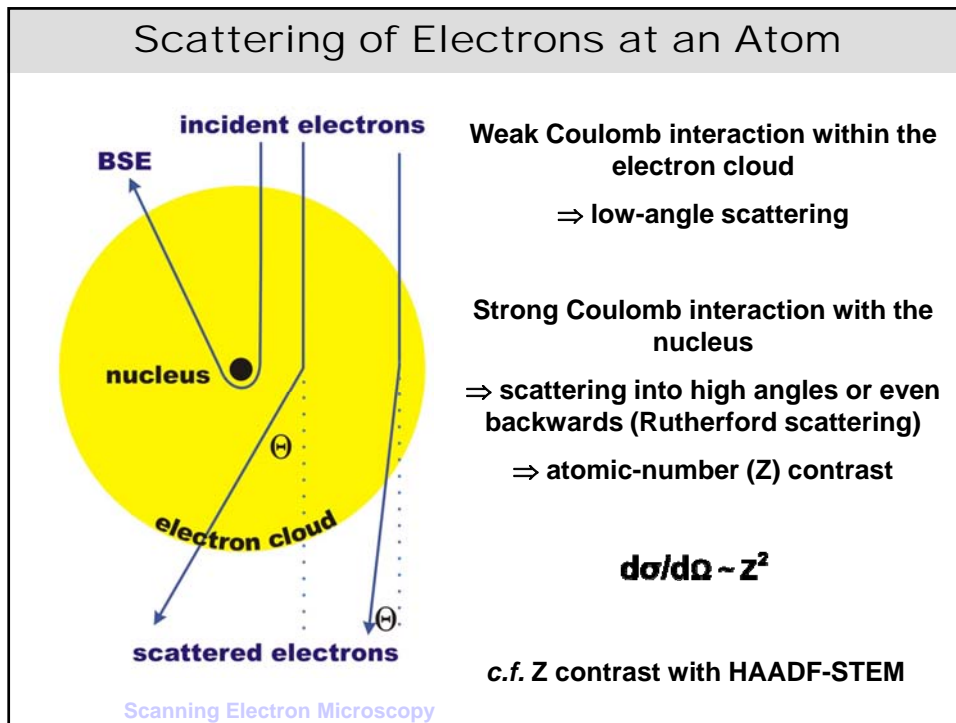
## SEM: Dependence on Electron Energy



Resolution (Gemini 1530 FEG):

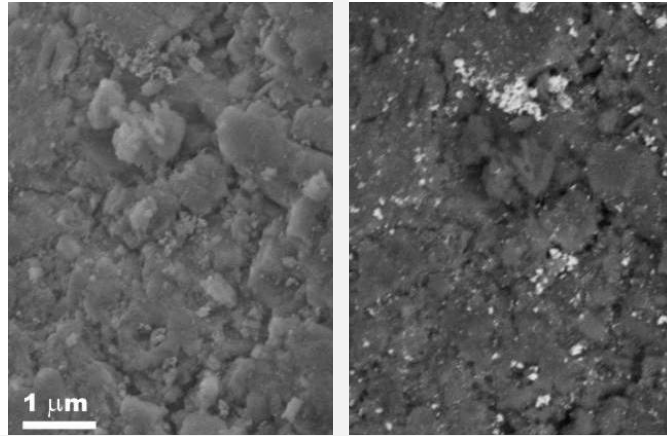
1 nm at 20 kV      1.5 nm at 10 kV  
2.5 nm at 1 kV      5 nm at 0.2 kV

Scanning Electron Microscopy



## SEM: Detection of SE versus BSE

### Pt particles on alumina



Secondary electron detector

Backscattered electron detector

Pt particles bright (Z contrast)

Scanning Electron Microscopy

## Scanning Electron Microscopy (SEM)

### Detection of:

- Secondary electrons
- Back-scattered electrons

### Determination of

- Morphology
- Surface topology
- Particles of heavy elements

### Combination with EDXS

Scanning Electron Microscopy

**Script: *Interactions.pdf* on  
[www.microscopy.ethz.ch/downloads](http://www.microscopy.ethz.ch/downloads)**

**Textbooks:**

**Williams, Carter, Plenum Press, New York, 1996:  
*Transmission Electron Microscopy (available in chemistry library)***

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**Lecture: *Electron Microscopy* (each fall term)**